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MAR 18 2005

March 18, 2005

VIA FACSIMILE
EXPEDITED PROCEDURE

To: Examiner David Vu Facsimile No. 703-872-9306
 Group Art Unit No. 2818
 U. S. P. T. O.

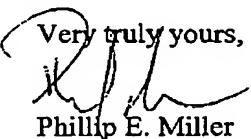
From: Phillip E. Miller Facsimile No. 703-761-2375

Re: Filing of Request for Consideration of IDS
 U. S. Patent Application Serial No. 10/725,380
 Our Ref: NGB.224DIV

Dear Examiner Vu:

Enclosed please find a Request for Consideration of IDS, which requests that you confirm you consideration of the IDS submitted on February 24, 2005 in this case.

Thank you in advance for your kind consideration of this case.

Very truly yours,

 Phillip E. Miller

PEM/lnb
 Enclosure

1
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
In re Application of

Naoki SHIBATA et al.

Serial No.: 10/725,380

Group Art Unit: 2818

Filed: December 3, 2003

Examiner: David Vu

For: GROUP III NITRIDE COMPOUND SEMICONDUCTOR DEVICE AND METHOD
OF PRODUCING THE SAME

Honorable Commissioner of Patents
Alexandria, VA 22313-1450

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MAR 18 2005

**REQUEST FOR CONSIDERATION OF
INFORMATION DISCLOSURE STATEMENT**

Sir:

Applicant respectfully requests that the Information Disclosure Statement filed on February 24, 2005 be officially considered of record. For the Examiner's convenience, another PTO-1449 form is attached hereto.

Applicant notes that the Examiner notified Applicant's undersigned representative via telephone on March 18, 2005, that the Examiner would consider the materials submitted in the IDS.

Therefore, Applicant respectfully requests that the Examiner officially acknowledge his consideration of the materials which were submitted in the Information Disclosure Statement filed on February 24, 2005..

Respectfully Submitted,



Phillip E. Miller
Reg. No. 46,060

Date: 3/18/05

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INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>			Docket Number (Optional)		Application Number		
			T36-163905M/RS		10/725,380		
			Applicant(s) Naoki Shibata, et al.				
			Filing Date	Group Art Unit			
			12/03/03	2818			
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
FOREIGN PATENT DOCUMENTS							
REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO
	02-081482	03/22/1990	JAPAN			ABS	
OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>							
		Japanese Office Action dated December 14, 2004 with English translation.					
		Heon Lee, et al. Growth of Thick GaN Films on RF Sputtered AlN Buffer Layer by Hydride Vapor Phase Epitaxy, Journal of Electric Materials, vol 26, No. 8 (1997) pp 898-902.					
EXAMINER			DATE CONSIDERED				
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

10/725,380
T36-163905M/RS

CERTIFICATE OF FACSIMILE TRANSMISSION

I hereby certify that the foregoing was filed by facsimile with the United States Patent and Trademark Office, Examiner David Vu, Group Art Unit #2818 at fax number (703) 872-9306 this 18th day of February, 2005.



Phillip E. Miller
Reg. No. 46,060